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Application No.: 10/603,924

APR - 4 2006

Docket No.: JCLA7109

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Examiner: NGUYEN, THANH T

Group Art Unit: 2813

In re PATENT APPLICATION of

Applicants : Shao-Chung Hu

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Serial No. : 10 / 603,924

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Filed : June 24, 2003

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For : POST-CMP REMOVAL OF SURFACE
CONTAMINANTS FROM SILICON WAFER)AMENDMENTAMENDMENT AFTER FINAL

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

*4/14/06.
TW*
The Office Action mailed December 5th, 2005 has been carefully considered. In response thereto, please enter the following amendments and consider the following remarks.